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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **OZAKI, Takashi, et al.**

Group Art Unit: 2813

Serial No.: 10/517,765

Examiner: **MCCALL SHEPARD, Sony**

Filed: **February 3, 2006**

P.T.O. Confirmation No.: 6791

FOR: SUBSTRATE TREATING APPARATUS AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE

RESPONSE UNDER 37 CFR §1.116

**- EXPEDITED RESPONSE -
GROUP ART UNIT 2813**

MAILSTOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

April 27, 2009

Sir:

In response to the Final Office Action dated December 1, 2008, extended from March 1, 2009 to May 1, 2009 by a two (2) month Petition for Extension of Time, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.

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